

L&L-I0242



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By: Yonghong Chen

Date: August 1, 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applic. No. : 10/694,593 Confirmation No. 3503
Applicant : Olaf Storbeck et al.
Filed : October 27, 2003
TC/A.U. : 2823
Examiner : Fernando L. Toledo
Title : Method for Minimizing the Vapor Deposition of
Tungsten Oxide During the Selective Side Wall
Oxidation of Tungsten-Silicon Gates

Docket No. : L&L-I0242

Customer No. : 24131

Hon. Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

S i r :

In response to the Office action dated May 11, 2005, please
amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of
claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 10 of this paper.